

IN THE CLAIMS:

Please amend claims 1 and 3-5 as follows:

- 1 1. (Currently Amended) A method of manufacturing a head slider,
2 comprising the steps of:
3 C1 forming a magnetizable layer on a surface of a substrate wafer having a
4 thickness greater than a length of the slider;
5 cutting said wafer into a plurality of raw bars after forming said layer while
6 said thickness of said wafer is still greater than said length of the slider;
7 supporting said plurality of raw bars by a supporting jig;
8 arranging dummy sections of said plurality of raw bars in a single direction;
9 forming air bearing surface patterns on air bearing surface faces of said
10 plurality of raw bars by photolithography; and
11 removing said dummy sections from [[the]] said plurality of raw bars after
12 forming said air bearing surface patterns.

- 1 2. (Previously Presented) The method according to claim 1, wherein
2 said plurality of raw bars have thicknesses greater than a length of said slider, and are
3 supported by said supporting jig in a machining step.

1 3. (Currently Amended) The method according to claim 1, wherein
2 said dummy sections of [[a]] said plurality of raw bars are arranged on one side in said
3 supporting jig.

1 4. (Currently Amended) The method according to claim 1, further
2 comprising the step of[[:]] cutting at least one of said plurality of raw [[bar]] bars so as to
3 form the slider.

1 5. (Currently Amended) The method according to claim 1, further
2 comprising the step of[[:]] removing the dummy section sections before cutting into at least
3 one of said plurality of raw [[bar]] bars.

1 6. (Withdrawn) A method of manufacturing a magnetic head, comprising
2 the steps of:
3 forming a plurality of layers including a magnetizable layer on a surface of a
4 substrate;
5 cutting said substrate so as to form a plurality of raw bars; and
6 removing a prescribed part of each raw bar, from one end face, in a direction of
7 piling said layers.

C / Concluded